

AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

Claim 1 (Currently Amended): A position indicator for detecting movement of a ~~pointing device~~ position indicator by moving the position indicator in the air, comprising: a pressure sensor to detect a reaction of air due to the movement of the ~~pointing device~~ position indicator.

Claim 2 (Original): The position indicator of Claim 1, wherein the pressure sensor comprised in the position indicator comprises an elastic film to push the air.

Claim 3 (Previously Presented): The position indicator of Claim 2, wherein the elastic film forms concavity to provide the maximum momentum to the air.

Claim 4 (Original): The position indicator of Claim 1, wherein the pressure sensor comprises a cover comprising minute holes in the front to prevent the pressure sensor from wind.

Claim 5 (Original): The position indicator of Claim 1, wherein the pressure sensor comprises holes on the back to make the air flow smoothly.

Claim 6 (Previously Presented): The position indicator of Claim 4, wherein the cover comprises a cover comprising another holes on the outside to prevent the pressure sensor from wind.

Claim 7 (Previously Presented): The position indicator of Claim 2, wherein the elastic film is comprised of a piezoelectric film having a piezoelectric effect.

Claim 8 (Previously Presented): The position indicator of Claim 7, wherein the piezoelectric film is glued to another film, comprised of a material with good elasticity and rigidity, which fills a role of pushing air.

Claim 9 (Currently Amended): The position indicator of Claim 2, wherein the reaction of the air due to the movement of the ~~pointing device~~ position indicator is calculated by measuring a change in an output of a photo sensor which receives a reflected light of a light emitted towards the elastic film.

Claim 10 (Previously Presented): The position indicator of Claim 2, wherein the elastic film is comprised of a silicon, a piezo resistive element is set near the elastic film and a deflection occurred by the elastic film pushing the air is measured by a change in a resistance value of the piezo resistive element.